

参考文献

- (1) 例えば、早川、和佐：“薄膜化技術”（共立出版, 1982）
P.17
- (2) 同上 P.116
- (3) T. Fukami and T. Sakuma: "Target Erosion Pattern in Planar Magnetron Sputtering", Jpn. J. Appl. Phys., 21 (1982) 1680.
- (4) F. Takeda, T. Hata: "Low Temperature Deposition of oriented C-Axis AlN Films on Glass Substrates by Reactive Magnetron Sputtering", Jpn. J. Appl. Phys., 19 (1980) 1001
- (5) 阿部、小林、龜井：“膜厚分布が制御可能なプレーナー型スパッタ電極” 真空、25 (1982) 61
- (6) 深海、新谷：“制御磁極を有する平板マグネットロニススパッタ装置の磁界分布と侵蝕領域” 昭和58年度電子通信学会信越支部大会、23
- (7) J.E. Greene, C.E. Wickersham, and J.L. Zilk: "Epitaxial growth of In_{1-x}Ga_xSb thin films by multi-target rf sputtering", J. Appl. Phys., 47, (1976), 2289
- (8) C.T. Foxon and B.A. Joyce: "INTERACTION KINETICS OF As₄ AND Ga ON {100} GaAs SURFACES USING A MODULATED MOLECULAR BEAM TECHNIQUE", Surface Science, 50, (1975), 434
- (9) T. Suntola, J. Antson, A. Pakkala and S. Lindfors: "Atomic Layer Epitaxy for Producing EL-Thin Films", SID 80 DIGEST, (1980), 108
- (10) 「コンピュータ要素を100倍以上も高速化する超格子素子」, 日経コンピュータ 1984.11.12, 79

- (11) A. YARIV, P. YEH : "OPTICAL WAVES IN CRYSTALS",
Wiley series in Pure and Applied Optics, 209
- (12) H. K. Wong, G. k. Wong, and J. B. Ketterson : "Ferroelectricity
and coherent phonon generation in piezoelectric composition-
modulated structures"; J. Appl. Phys., 53, (1982), 6834
- (13) 上田, 池上 : "PbTiO₃ 磁器压電体 (MLT)",
National Technical Report, 15, (昭和 44) 643
- (14) K. KUSAO, K. WASA, S. HAYAKAWA : "Electrical Properties of
Mixed Oxide Film of PbO and TiO₂", JAPAN. J. Appl. Phys.,
7 (1968) 437
- (15) エレセラ出版委員会 : "セラミックセニア", (学南社 1980)
191
- (16) M. OKUYAMA, Y. MATSUI, H. NAKANO, T. NAKAGAWA :
"Preparation of PbTiO₃ Ferroelectric Thin Film by RF
sputtering", Jpn. J. Appl. Phys., (1979) 1633
- (17) J. J. Hank, H. W. Lehmann, R. K. Wehner : "Calculation of
Deposition Profiles and Compositional Analysis of Cospattered
Films", J. Appl. Phys., 43, (1972) 1666
- (18) T. Fukami, T. Sakuma, K. Tokunaga, H. TSUCHIYA : "Ferroelectric
Films Deposited by Reactive Sputtering and Their Properties",
Proceedings of the 4th Meeting on Ferroelectric Materials and Their
Applications, Kyoto 1983 Jpn. J. Appl. Phys., 22, (1983) 18

(19) Y. Matsui, M. Okuyama, N. Fujita: "Laser annealing to produce ferroelectric-phase $PbTiO_3$ thin films", *J. Appl. Phys.*, 52

(1981) 5/10/7

(20) 金原: 「スピタリニク現象」 (東京大学出版会 1984)

101

(21) S. Craig, G. L. Harding: "Effect of argon pressure and substrate temperature on the structure and properties of sputtered copper films", *J. Vac. Sci. Tech.*, 19 (1981)

(22) 岡崎: 「セラミック誘電体工学」, (学術社 1978
増補版), 14

(23) 電子材料工業会: 「表面波デバイスとその応用」,
(学術社 1978 増補版), 14

(24) W. R. SMITH, H. M. GERARD, J. H. COLLINS, T. M. REEDER

: "Analyses of Interdigital Surface Wave Transducers by Use
of an Equivalent Circuit Model", *IEEE TRANS., MTT-
17*, 11 (1969) 856

(25) G. S. KINO, R. S. WAGERS: "Theory of interdigital couplers on
nonpiezoelectric substrates", *J. Appl. Phys.*, 44 (1973) 1480

(26) 柴山乾夫: 「強性表面波工学」, (コロナ社 1983) 69

(27) 杉原、宇田、陣田、実吉、村川: "FET型湿度
センサ (I) - 結晶化 PVA 膜特性 -"

- (28) H. ITO : "Humidity Sensor by Quarts Oscillator with Epoxy Resin as a Hygroscopic Film", PROCEEDINGS OF THE 3RD SENSOR SYMPOSIUM, (1983) 229
- (29) T. M. Reeder, D.E. Cullen, M. Gilden : "SAW OSCILLATOR PRESSURE SENSORS", 1975 Ultrasonics Symposium Proceedings, IEEE Cat. 264

E. GATTI, A. PALMA, E. VERONA : "A SURFACE ACOUSTIC WAVE VOLTAGE SENSOR", Sensors and Actuators, 4 (1983) 45.

その他

- (30) A. BRYANT, M. POIRIER, G. RILEY, D.L. LEE, J.F. VETELINO : "GAS DETECTION USING SURFACE ACCOSTIC WAVE DELAY LINES", Sensors and Actuators, 4 (1983) 105
- (31) A. D'AMICO, A. PALMA, E. VERONA : "SURFACE ACOUSTIC WAVE HYDROGEN SENSOR", Sensors and Actuators, 3 (1982/83) 31
- (32) P. MOY, F.E. KARASZ : "The Interactions of Water with Epoxy Resins", 1980 American Chemical Society, 30, 506
- (33) 戸田, 桜井, 川端, 田中: "PZT磁器板上の表面弹性波", 電子通信学会論文誌, 53-A (1970) 89

(34) 薄膜スパッタと厚膜印刷の2方法で作った強誘電体の焦電型赤外センサ、日経エレクトロニクス、

8.1 (1983) 63

(A1) 横岡, 二瓶: 「フォトエッチングと微細加工」, (工学図書 昭和52), (全編を通して利用)

(A2) 甲川, 和佐: 「薄膜化技術」, (共立出版 1983) 24
および 78